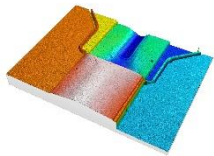
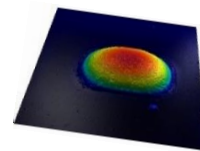


SURFIEW 6000



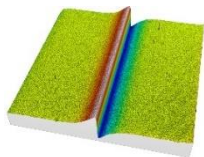
Semiconductor

Stud Bump	直径, 高度, 体积, 粗糙度, 角度
CMP	Warpage, 粗糙度
CVD	粗糙度
Wafer	Warpage, 划痕, 粗糙度



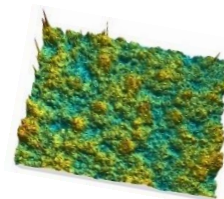
PCB

Substrate (Pad, Trace, Space, Anchor, Land, Ball Pad, Via Hole, Dimple, SR)	高度, 宽度, 深度, 直径, 厚度, 体积, 粗糙度, Roundness
BGA	Ball 高度, 直径, Coplanarity



Display

Photo Space	直径, 高度, 宽度, 体积
RGB	厚度, 粗糙度, BM 厚度
TFT Pattern	高度, 宽度, 粗糙度
BLU	角度, 宽度, 高度, 粗糙度
Metal Jet	宽度, 高度, 角度, 粗糙度
Glass	Defect 形态, 宽度, 高度
OLED	蒸镀高度, 角度, 体积



ETC

MEMS	高度, 宽度
Precision machine part	粗糙度, 高度, 宽度
Laser Marking	深度, 体积
Inkjet	体积, 高度, 面积
Micro Lens	曲率, 高度
RFID	高度, 宽度, 粗糙度

Specification

SURFIEW 6000

Vertical Resolution	VSI,VEI < 0.5nm, VPI < 0.1nm
Lateral Resolution	0.05~7.2um(Depends on magnification)
Height Repeatability	≤0.1% @ 1σ
Objective Lens	5 Selectable(Automatic)
Zoom Lens	3 Selectable(0.55x/1.0x/1.5x @ Automatic)
Camera Format	1/2" Mono Camera
Scan Method	Piezo Actuator@Capacity Closed loop
PZT Scan Range	≤300um
Scan Speed	7.5um/sec(1x) / 22.5um/sec(3x)
Illumination	White LED
Filter	Visible/Bandpass/Green Filter(Auto)
Auto Focus	Yes
X/Y Axis Stroke	600mm(X) x 600mm(Y)
Z Aixe Stroke	50mm
Tilt Aixe Stroke	None
Work Table Size	650mm X 650mm (Vacuum Type)
Max Workpiece Load	≤ 10kg
Layout Size	2200mm(W) x 1800mm(D) x 2100mm(H)
Software	Surface View/Surface MAP@ Window10 (64bit)
Stitching	Yes
Vibration Isolation Platform	Passive Type(Vertical Resonance: 1.5Hz)
Input Power	2 φ ,110V/220V(± 10%), 50/60Hz

Option

Interference Lens	2.5x, 5.0x, 10x, 20x, 50x, 100x
Objective Lens	2.5x, 5.0x, 10x, 20x, 50x, 100x
Zoom Lens	0.55x, 0.75x, 1.0x, 1.5x, 2.0x
Motor Scan	≤10mm@Linear Scale
Laser Auto Focus	Option
Camera Format	2/3" or 1" Mono Camera
Work Table	Vacuum Table, Rotation Table



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